

Amod

Deposition Sources

With its 500 mm x 500 mm baseplate, your Amod can accommodate up to 10 sources and a wide variety of PVD processes. The chamber can be integrated to a **glovebox**, a **cleanroom wall**, or selected in a standalone configuration. With our standard chamber height of 500 mm, your Amod system is very customizable to your process requirements.

Sputtering

RF, DC, pulsed DC, reactive gas, and HiPIMS Circular, linear & cylindrical cathodes available

Thermal Evaporation

Wide range of boats, filaments & crucible heaters Auto-tuning ensures precise rate control and simple setup

Electron Beam Evaporation

Wide range of source and power supply options Programmable sweep controller with recipe storage Torque sensing crucible indexer detects pocket jams

Plasma and Ion Beam Processing

Range of ion sources for cleaning & film enhancements Glow discharge plasma cleaning

Vacuum Control

Your Amod can be configured for **high vacuum (HV)** or **ultra-high vacuum (UHV)** utilizing a turbo pump or cryo pump. Chamber construction can be high-purity aluminum or stainless steel using Viton or metal gaskets. We can help you decide what is best for your application.

Our team of engineers, chemists, and nanotechnologists will help design the best tool for your process and material requirements. We offer support and can optimize your system for film thickness uniformity, film structure and material utilization.

Please call us to discuss your application in detail.

Substrate Fixturing and Masking



ANGSTROM

Heated, Cooled, & Biased Stages

LN2/GN2 cooling to -170 °C Heating to 900 °C Auto-calibration via AERES software RF or DC stage biasing

Roll to Roll Processing

Servo wind and unwind for precise speed and tension control
Allows flexible substrate coating using production technology
Process is scalable for high throughput

Load Locks & Mask Handling

Manual, semi-auto or full-auto substrate and mask handling Options for single substrate or high capacity parking chambers

Masking Shutter

Two programmable shutters selectively expose rows and columns in a sample matrix, creating many unique samples in a single run

Variable Angle Stages

Comformally coat 3D features
Create complex nano-structures
-95 ° to 95 ° tilt with continuous rotation
Heating and cooling options available

Planetary & Dome Fixturing

Domed substrate carrier for lift-off and batch processes Planetary motion & flip fixturing available

"We have several labs with over \$2M of equipment from 30+ vendors and Angstrom Engineering has the best customer service. I like the people there, how they will work side by side with their customers to meet their needs.

Dr. Quyen Nguyen University of California Santa Barbara

AERES Integrated Software

Simple to use yet can handle the most complex process recipes PC/PLC controlled recipes for single, batch, or fully automated processes Advanced data logging and process tracking ensure consistent and repeatable processes High resolution control provides impressive low rate stability and consistent doping ratios Automatic PID control loop tuning significantly reduces process development time

Your Amod can be everything you need it to be:



Cadmium telluride photovoltaic deposition system

Noble metal UHV evaporation system





Dielectric optical sputtering system for broadband filters

Service and Support: Our Commitment

An Angstrom system in your lab makes us partners; we become part of your team.

We guarantee **same day** response to any service inquiry regarding parts, technical support, and software support.

